

<b>Notice of References Cited</b>	Application/Control No. 10/080,539	Applicant(s)/Patent Under Reexamination Kagoshima et al.	
	Examiner Karla Moore	Art Unit 1763	Page 1 of 1

**U.S. PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
	A	US-5,135,608	08-1992	Okutani, Ken	438/584
	B	US-5,310,410	05-1994	Begin et al.	29/25.01
	C	US-5,474,641	12-1995	Otsuki et al.	438/694
	D	US-5,766,360	06-1998	Sato et al.	118/666
	E	US-5,769,952	06-1998	Komino, Mitsuaki	118/733
	F	US-5,934,856	08-1999	Asakawa et al.	414/217
	G	US-5,963,329	10-1999	Conrad et al.	356/613
	H	US-6,106,659	08-2000	Spence et al.	156/345.43
	I	US-6,264,748	07-2001	Kuriki et al.	118/719
	J	US-2002/0155629	10-2002	Fairbairn et al.	438/14
	K	US-			
	L	US-			
	M	US-			

**FOREIGN PATENT DOCUMENTS**

*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Country	Name	Classification
	N					
	O					
	P					
	Q					
	R					
	S					
	T					

**NON-PATENT DOCUMENTS**

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	M.E. Lee et al., Analysis of Reflectometry and Ellipsometry Data from Patterned Structures, Characterization and Metrology for ULSI Technology: 1998 International Conference, The American Institute of Physics 1998.
	V	
	W	
	X	

\*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)  
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.